IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor(s)

Josef WEIDMANN et al.

Serial No.

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For

REFLECTOMETER AND METHOD FOR MANUFACTURING A REFLECTOMETER

Examiner

To Be Assigned

Art Unit

To Be Assigned

Assistant Commissioner for Patents Washington, D.C. 20231

SECOND PRELIMINARY AMENDMENT

SIR:

Kindly amend the above-captioned application before examination, as set forth below.

IN THE CLAIMS:

Please cancel claims 20 to 38 without prejudice.

Please add the following new claims:

36 -39. (New) A reflection graduation, comprising:

a silicon substrate;

first subsections disposed on the substrate, each of the first subsections having etched oblique surfaces, the surfaces positioned such that light beams directed incident to the surfaces cause no retroreflection; and

second subsections having relatively higher reflecting properties as compared to the first subsections;

wherein the first subsections and the second subsections are alternatively disposed on the substrate in a first direction.

346. (New) The reflection graduation as recited in claim 39, wherein the oblique surfaces include a plurality of adjacent V-shaped grooves disposed in a

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